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Form 1449 (Modified)

Atty. Docket No. Application No.:

NAI1P066/01.308.01

Information Disclosure
Statement By Applicant

V. Iyer et al.

Filing Date:

Group Art Unit:

(Use Several Sheets if Necessary)

**U.S. Patent Documents** 

01/04/2002

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			U.S. I	Patent Documents_			
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Foreign Patent or Published Foreign Patent Application

Examiner		Document	Publication	Country or		Sub-	Trans	lation
Initial,	No.	No.	Date	Patent Office	Class	class	Yes	No
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## Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
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Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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Form 144 (Modified)

Atty Docket No.

Application No.:

NAIIP066

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Information Disclosure
Statement By Applicant

V. Iyer et al.

Filing Date: 2800

(Use Several Sheets if Necessary)

Group Art Unit:

Unassigned

- U.S. Patent Documents

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Foreign Patent or Published Foreign Patent Application

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## Other Documents

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Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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